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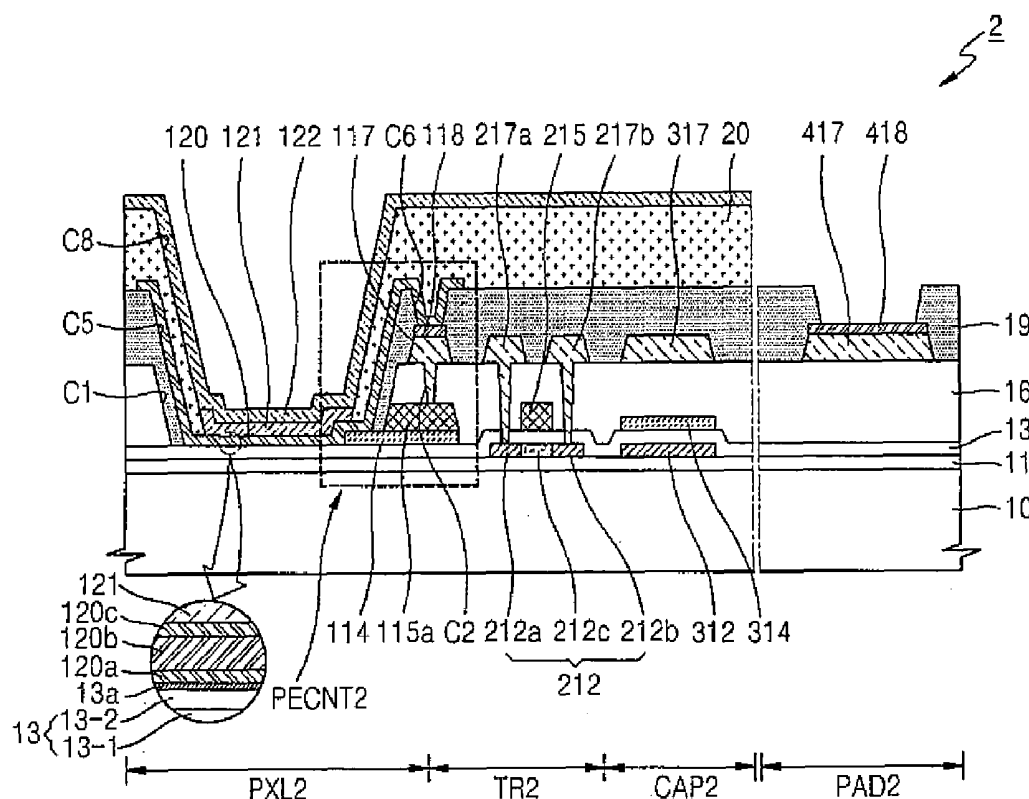


FIG. 1

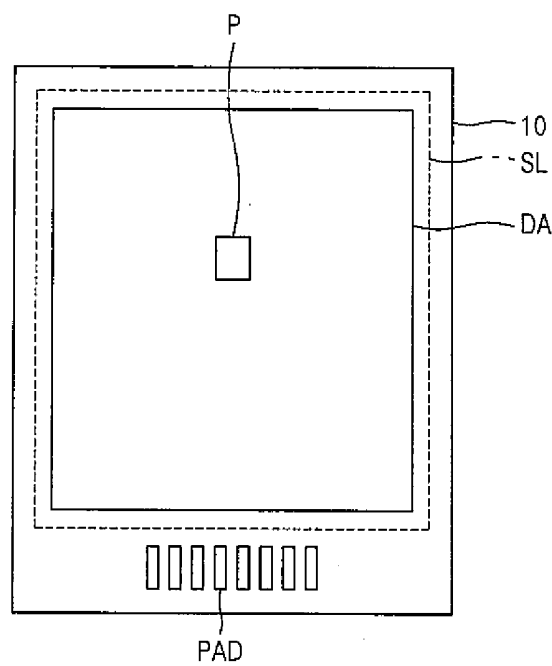


FIG. 2

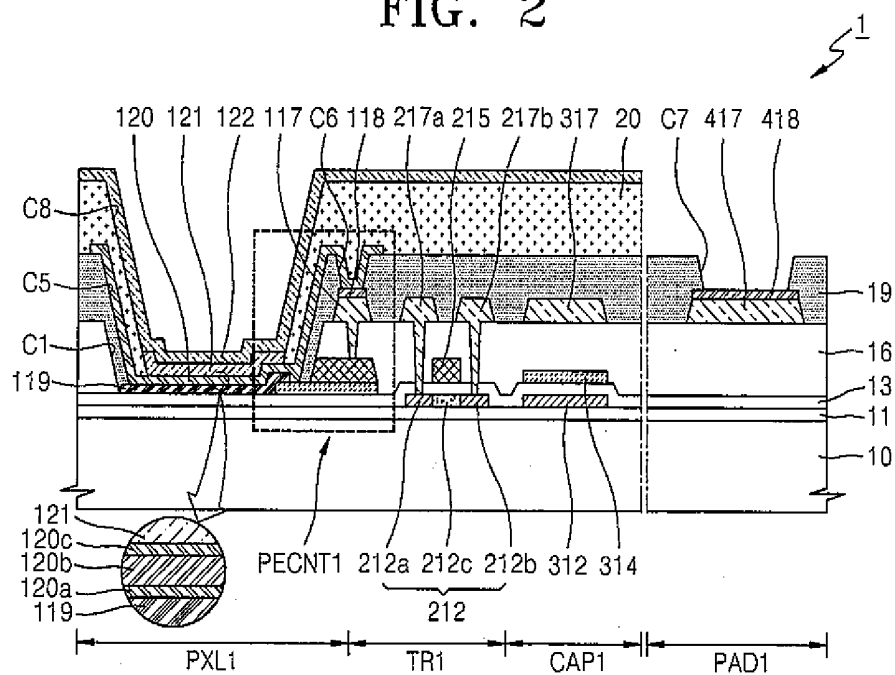


FIG. 3A

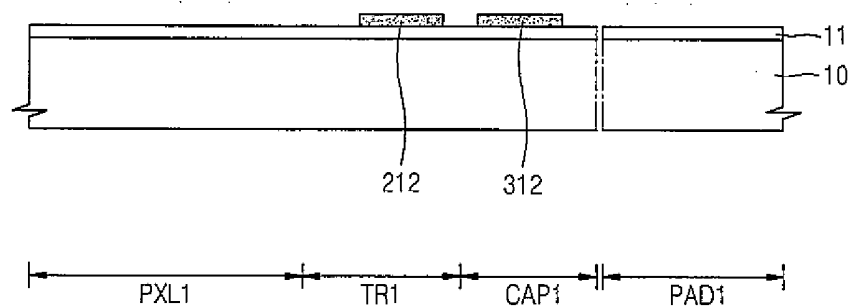


FIG. 3B

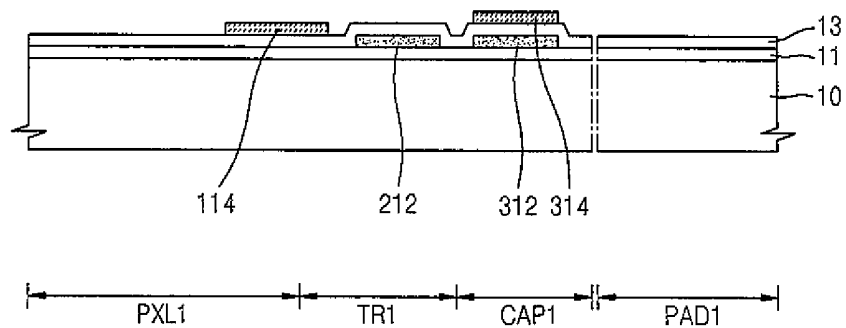


FIG. 3C

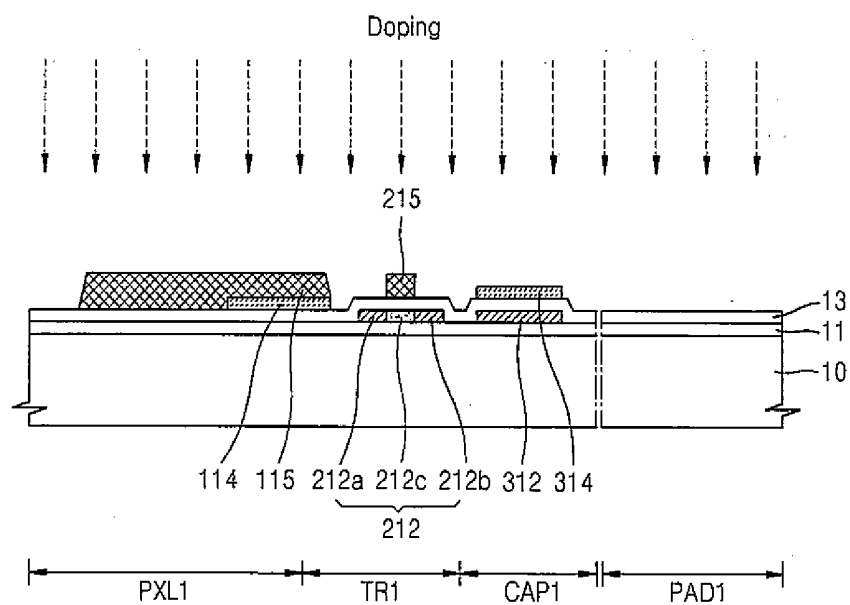


FIG. 3D

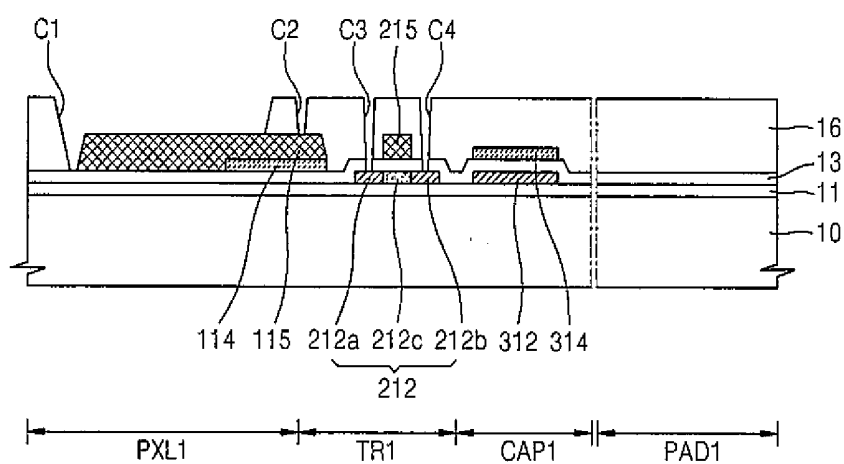
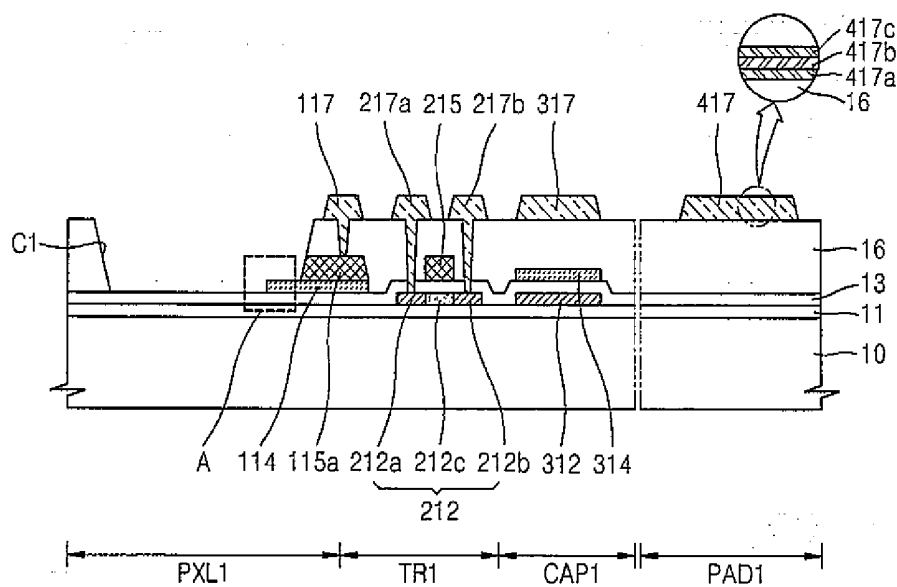


FIG. 3E



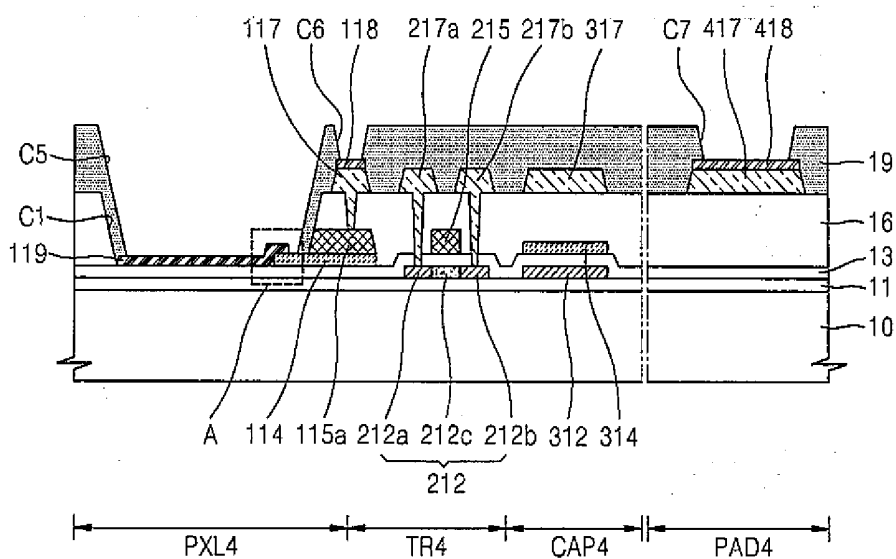


FIG. 3H

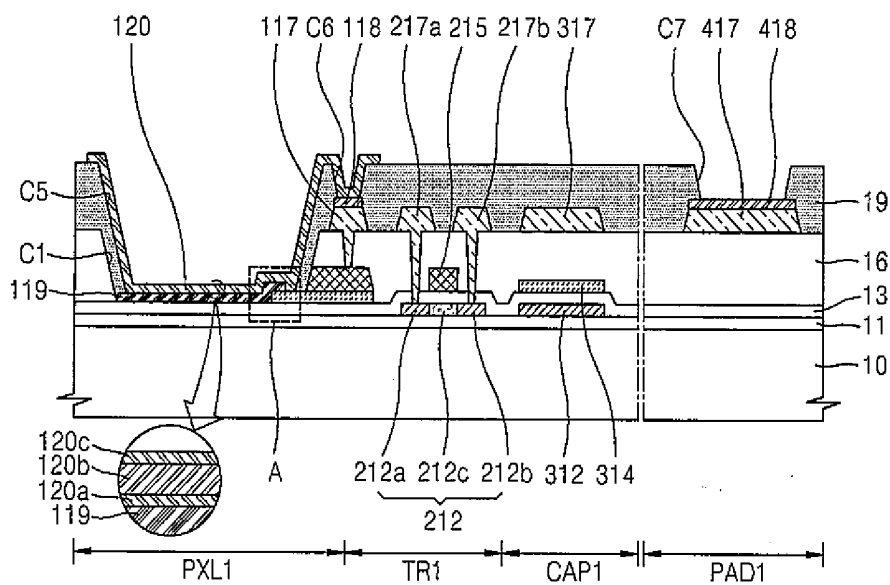


FIG. 3I

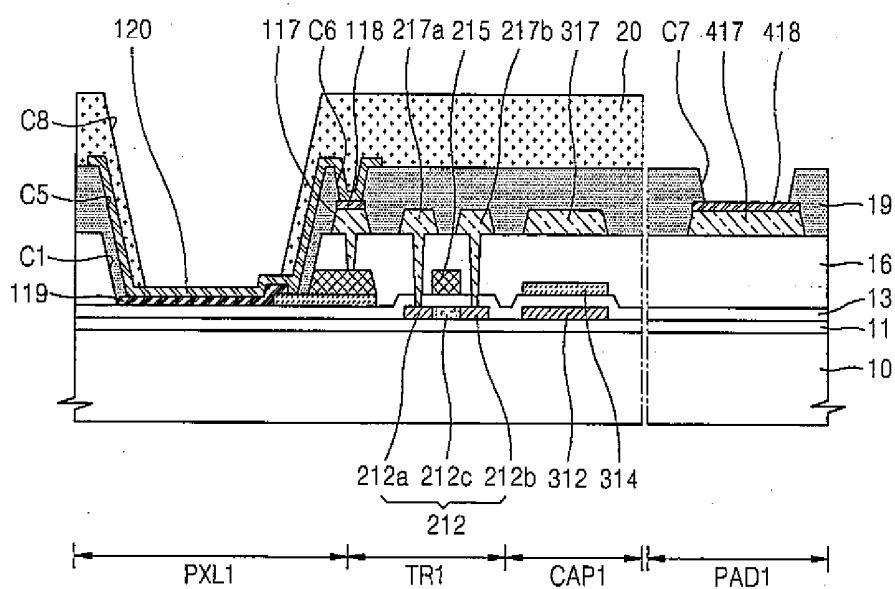


FIG. 4

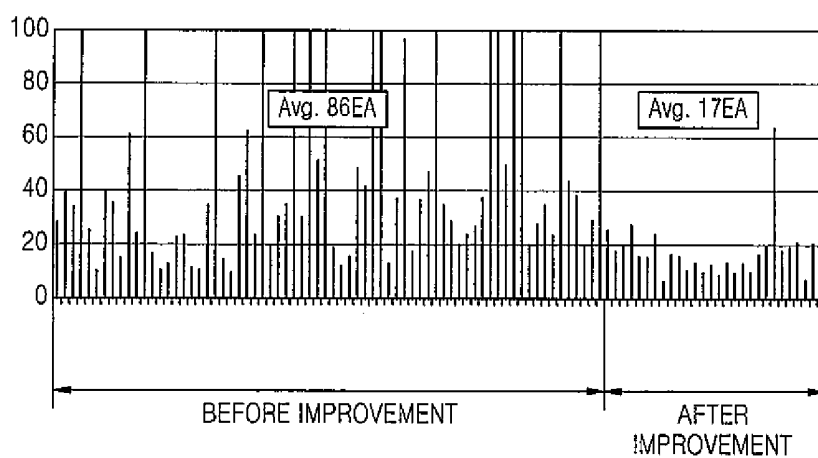
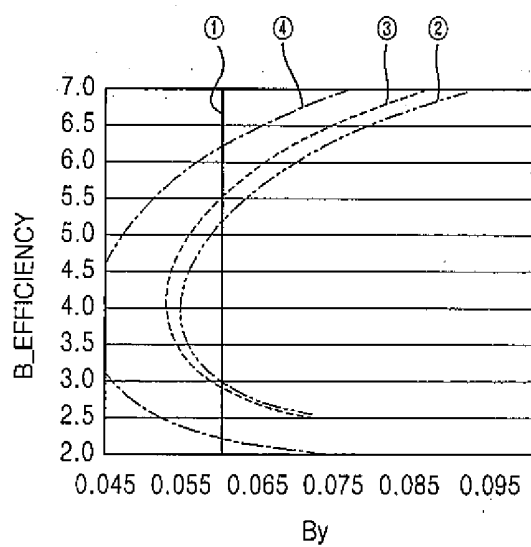


FIG. 5



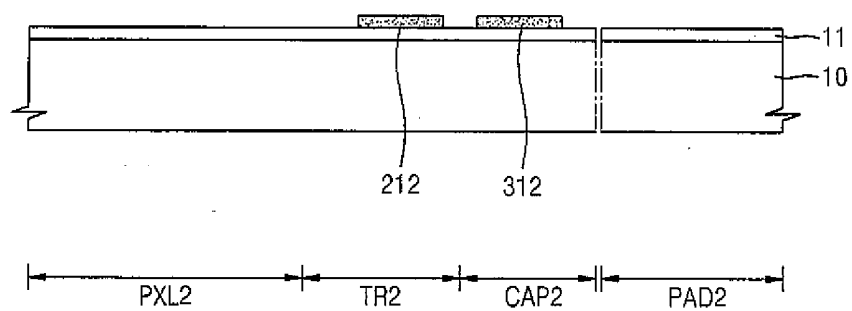


FIG. 7B

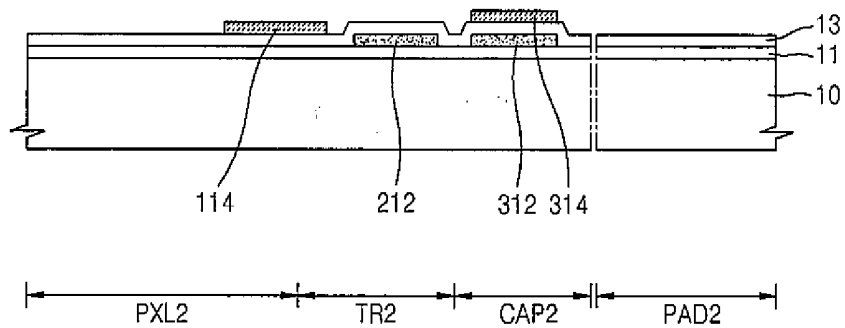


FIG. 7C

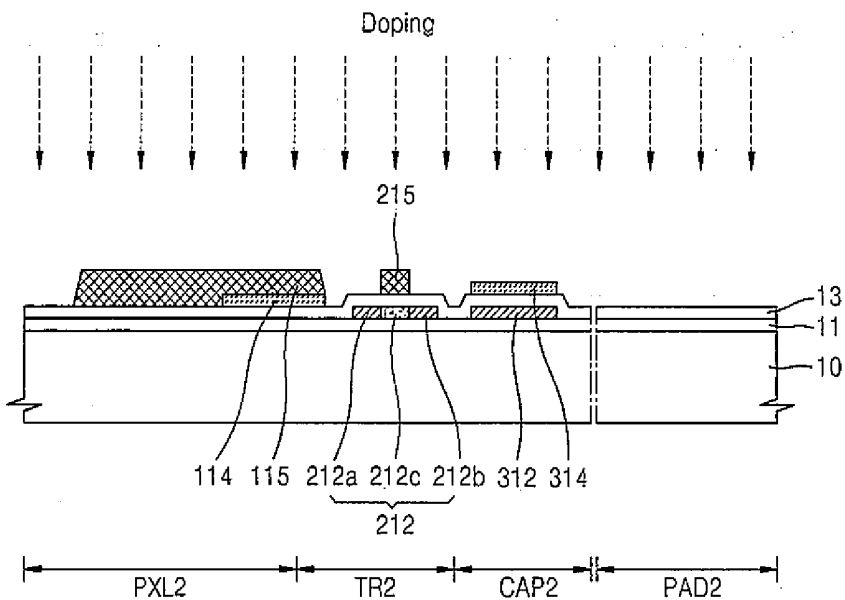


FIG. 7D

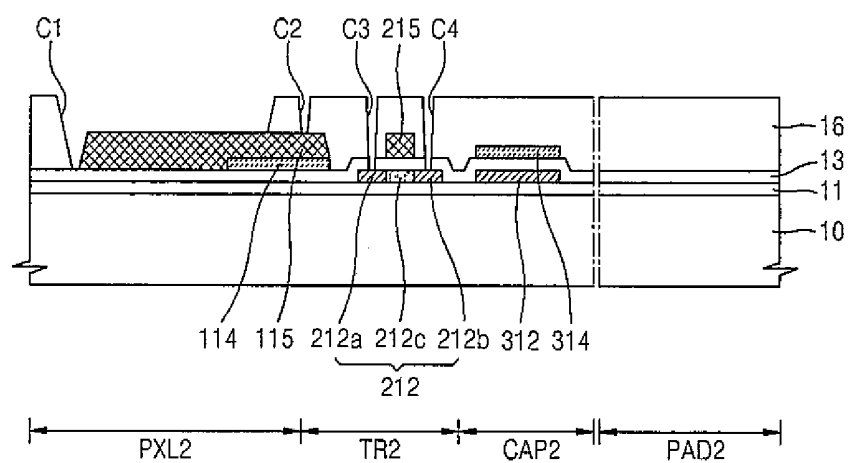


FIG. 7E

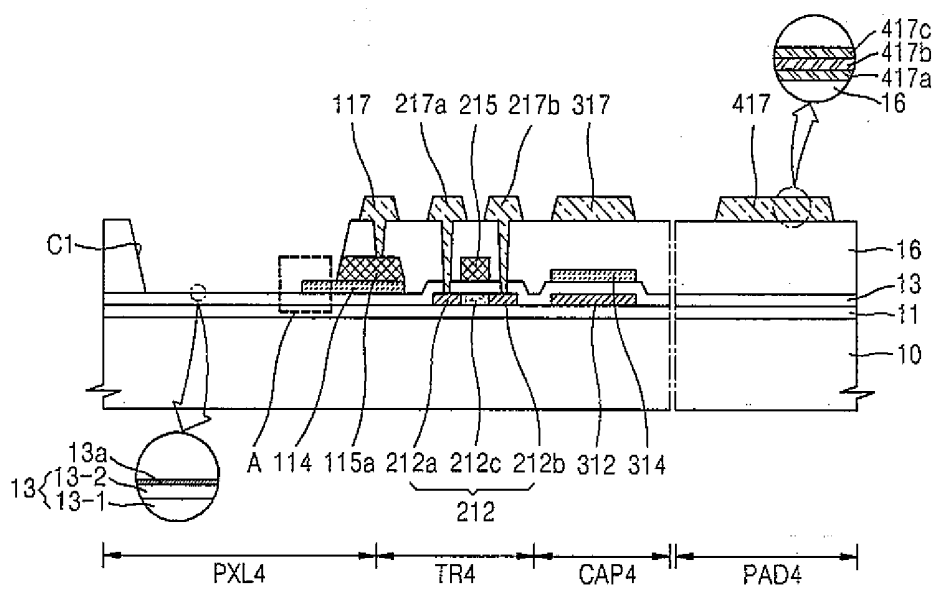


FIG. 7F

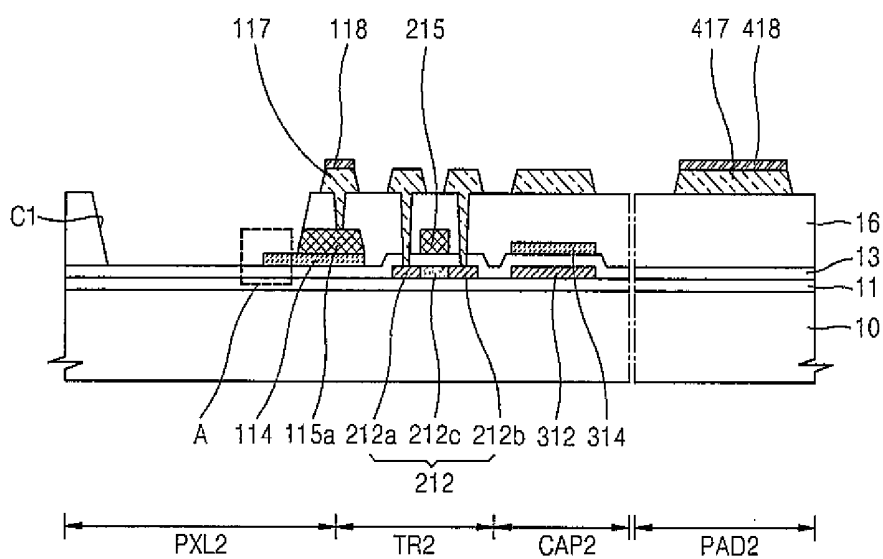


FIG. 7G

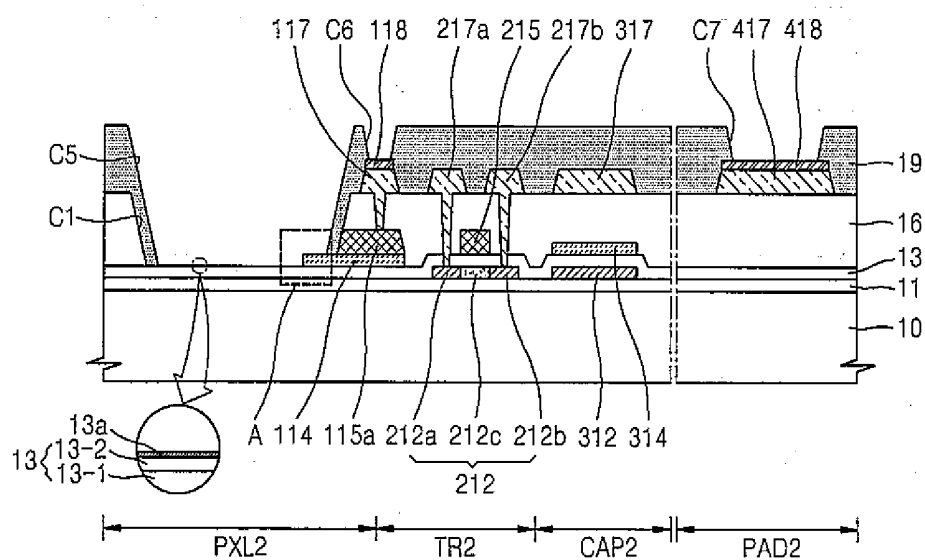


FIG. 7H

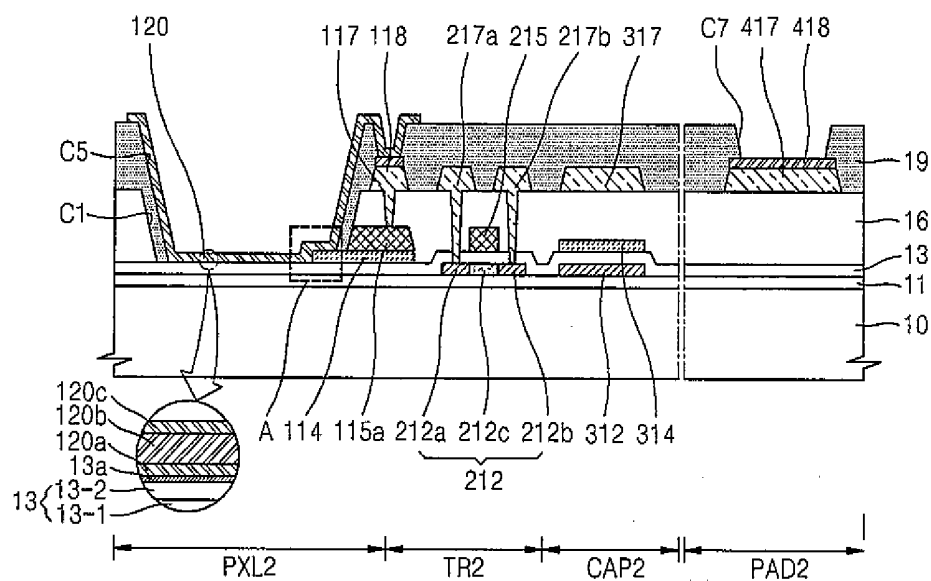
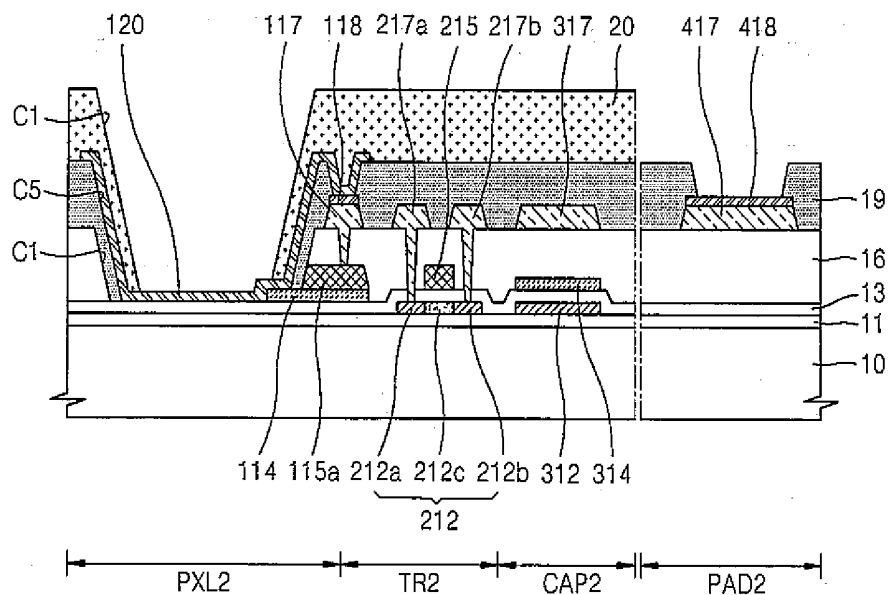


FIG. 7I



**ORGANIC LIGHT-EMITTING DISPLAY
APPARATUS AND METHOD OF
MANUFACTURING THE SAME**

**CROSS-REFERENCE TO RELATED
APPLICATION**

[0001] This application claims priority to and the benefit of Korean Patent Application No. 10-2013-0062114, filed on May 30, 2013, in the Korean Intellectual Property Office, the disclosure of which is incorporated herein in its entirety by reference.

BACKGROUND

[0002] 1. Field

[0003] Embodiments of the present invention relate to an organic light-emitting display apparatus and a method of manufacturing the same.

[0004] 2. Description of the Related Art

[0005] An organic light-emitting diode (OLED) display apparatus generally includes a hole injection electrode, an electron injection electrode, and an organic light-emitting layer formed therebetween. The OLED display apparatus is a self light-emitting display apparatus that emits light when holes injected from the hole injection electrode and electrons injected from the electron injection electrode recombine in the organic light-emitting layer to an excited state that gradually disappears thereafter.

[0006] Because of its high quality characteristics compared to other types of display devices, such as relatively low power consumption, relatively high brightness, and relatively fast response speed, the OLED display apparatus has received attention as a next generation display.

SUMMARY

[0007] Embodiments of the present invention provide an organic light-emitting display apparatus having an excellent display quality and a method of manufacturing the same.

[0008] According to an aspect of the present invention, there is provided an organic light-emitting display apparatus including: an active layer, a gate electrode, a source electrode, a drain electrode, a first insulating layer between the active layer and the gate electrode, and a second insulating layer between the gate electrode and the source and drain electrodes; a pad electrode including a first pad layer at a same layer as the source electrode and the drain electrode and a second pad layer on the first pad layer; a third insulating layer covering the source electrode and the drain electrode and an end portion of the pad electrode; a pixel electrode including a semi-transmissive electrically conductive layer in an opening in the third insulating layer; a transparent protection layer between the pixel electrode and the first insulating layer; a fourth insulating layer having an opening in a location corresponding to the opening formed in the third insulating layer, the fourth insulating layer covering the end portion of the pad electrode; an emission layer on the pixel electrode; and an opposing electrode on the emission layer.

[0009] The transparent protection layer may include a same material as the second pad layer.

[0010] The second pad layer may include a transparent conductive oxide.

[0011] The transparent protection layer may include one or more selected from the group consisting of indium tin oxide

(ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In_2O_3), indium gallium oxide (IGO), and aluminum zinc oxide (AZO).

[0012] A thickness of the transparent protection layer may be in a range of 200 Å and 800 Å.

[0013] The source electrode and the drain electrode may have a stack structure of a plurality of heterogeneous electrically conductive layers having different electron mobility.

[0014] The source electrode and the drain electrode may include a layer including molybdenum and a layer including aluminum.

[0015] The organic light-emitting display apparatus may further include: a capacitor including a first electrode at a same layer as the active layer and a second electrode at a same layer as the gate electrode.

[0016] The first electrode of the capacitor may include a semiconductor material doped with ion impurities.

[0017] The second electrode of the capacitor may include a transparent conductive oxide.

[0018] The capacitor may further include a third electrode at a same layer as the source electrode and the drain electrode.

[0019] The organic light emitting display apparatus may further include a pixel electrode contact unit electrically coupled between the pixel electrode and one of the source electrode and the drain electrode through a contact hole formed in the third insulating layer, wherein the pixel electrode contact unit includes: a first contact layer including a same material as the source electrode and the drain electrode; a second contact layer including a same material as the second pad layer; and a third contact layer in the first insulating layer and the second insulating layer and including a same material as the second electrode of the capacitor, wherein the first contact layer is electrically coupled to the third contact layer through a contact hole formed in the second insulating layer.

[0020] An end portion of the third contact layer may be on a top end of the opening formed in the third insulating layer.

[0021] An end portion of the third contact layer may protrude from an etching surface of an opening formed in the second insulating layer and may directly contact the pixel electrode.

[0022] An end portion of the third contact layer may protrude from an etching surface of an opening formed in the third insulating layer and may directly contact the pixel electrode.

[0023] The pixel electrode contact unit may further include a fourth contact layer between the first insulating layer and the third insulating layer and including a same material as the gate electrode.

[0024] An end portion of the third contact layer may protrude from an etching surface of an opening formed in the third insulating layer and may directly contact the transparent protection layer.

[0025] The first pad layer may include a same material as the source electrode and the drain electrode.

[0026] The semi-transmissive electrically conductive layer may include silver (Ag) or a silver alloy.

[0027] A protection layer may be stacked on at least one surface of the semi-transmissive electrically conductive layer.

[0028] The protection layer may include a transparent conductive oxide.

[0029] An opening in the second insulating layer, the opening in the third insulating layer, and the opening in the fourth insulating layer may overlap with each other, and a width of the opening in the third insulating layer may be greater than a

width of the opening formed in the fourth insulating layer and smaller than a width of the opening formed in the second insulating layer.

[0030] The opposing electrode may include a reflective electrically conductive layer.

BRIEF DESCRIPTION OF THE DRAWINGS

[0031] The above and other features and aspects of embodiments of the present invention will become more apparent by describing in detail exemplary embodiments thereof with reference to the attached drawings in which:

[0032] FIG. 1 is a schematic plan view illustrating an organic light-emitting display apparatus according to an embodiment of the present invention;

[0033] FIG. 2 is a schematic cross-sectional view illustrating a part of a pixel and a pad of an organic light-emitting display apparatus according to an embodiment of the present invention;

[0034] FIGS. 3A through 3I are schematic cross-sectional views illustrating a method of manufacturing the organic light-emitting display apparatus of FIG. 1, according to an embodiment of the present invention;

[0035] FIG. 4 is a graph illustrating a number of dark spot defects of an organic light-emitting display apparatus before and after a transparent protection layer is applied under the same condition according to an embodiment of the present invention;

[0036] FIG. 5 is a graph illustrating a relationship between a y color coordinate and efficiency of a blue emission layer with respect to a thickness of a transparent protection layer;

[0037] FIG. 6 is a schematic plan view illustrating an organic light-emitting display apparatus according to a comparison example; and

[0038] FIGS. 7A through 7I are schematic cross-sectional views illustrating a method of manufacturing the organic light-emitting display apparatus of FIG. 6, according to a comparison example.

DETAILED DESCRIPTION OF THE INVENTION

[0039] Embodiments of the present invention will now be described more fully with reference to the accompanying drawings for those of ordinary skill in the art to be able to perform the present invention without any difficulty. The invention may, however, be embodied in many different forms and should not be construed as being limited to the embodiments set forth herein; rather, these embodiments are provided so that this disclosure will be thorough and complete, and will fully convey the concept of the invention to those of ordinary skill in the art.

[0040] Also, parts in the drawings unrelated to the detailed description are omitted to ensure clarity of the present invention. Like reference numerals in the drawings denote like elements.

[0041] In various embodiments, elements having the same structure denoted by the same reference numeral are exemplarily explained in a first embodiment, and structures other than those in the first embodiment will be explained in other embodiments.

[0042] Also, sizes and thicknesses of elements in the drawings are arbitrarily shown for convenience of explanation, and thus are not limited to those as shown.

[0043] Various layers and regions are enlarged for clarity in the drawings. Thicknesses of some layers and regions are

exaggerated for convenience of explanation in the drawings. It will also be understood that when a layer, film, region, or plate is referred to as being “on” another layer, film, region, or plate, it can be directly on the other layer, film, region, or plate, or intervening layers, films, regions, or plates may also be present therebetween.

[0044] Unless the context dictates otherwise, the word “comprise” or variations such as “comprises” or “comprising” is understood to mean “includes, but is not limited to” such that other elements that are not explicitly mentioned may also be included. Also, it will be understood that the term “on” encompasses orientations of both “over” and “under” without being limited to “over” in a direction of gravity. As used herein, the term “and/or” includes any and all combinations of one or more of the associated listed items. Expressions such as “at least one of,” when preceding a list of elements, modify the entire list of elements and do not modify the individual elements of the list.

[0045] FIG. 1 is a schematic plan view illustrating an organic light-emitting display apparatus 1 according to an embodiment of the present invention. FIG. 2 is a schematic cross-sectional view illustrating a portion of a plurality of pixels P and a plurality of pads PAD of the organic light-emitting display apparatus 1 according to an embodiment of the present invention.

[0046] Referring to FIG. 1, a display area DA that includes the plurality of pixels P and displays an image is provided on a substrate 10 of the organic light-emitting display apparatus 1 according to an embodiment of the present invention. The display area DA is formed in a sealing line SL and includes a sealing member (not shown) that seals the display area DA along the sealing line SL. A cathode contact unit for supplying power to a cathode that is commonly formed in the display area DA may be formed between the display area DA and the pads PAD.

[0047] Referring to FIG. 2, a pixel area PXL1 including at least one organic emission layer 121, a transistor area TR1 including at least one thin film transistor, a capacitor area CAP1 including at least one capacitor, and a pad area PAD1 are provided on the substrate 10.

[0048] An active layer 212 of the thin film transistor is provided (e.g., formed, deposited, or positioned) on the substrate 10 and a buffer layer 11 is included (e.g., formed or deposited) in the transistor area TR1.

[0049] The substrate 10 may be a transparent substrate, such as a plastic substrate including polyethylene terephthalate (PET), polyethylene naphthalate (PEN), and polyimide as well as a glass substrate.

[0050] The buffer layer 11 forms a planar surface and prevents impurity elements from penetrating into the substrate 10, and may extend across the surface of the substrate 10. The buffer layer 11 may have a single layer structure or a multi-layer structure including silicon nitride and/or silicon oxide.

[0051] The active layer 212 on the buffer layer 11 is included (e.g., formed, deposited, or located) in the transistor area TR1. The active layer 212 may be formed of a suitable semiconductor material such as amorphous silicon or crystalline silicon. The active layer 212 may include a channel area 212c, a source area 212a provided in the outside of the channel area 212c and doped with ion impurities, and a drain area 212b. The active layer 212 is not limited to amorphous silicon or crystalline silicon, and may include an oxide semiconductor or other suitable semiconductor materials.

[0052] A gate electrode **215** is provided on the active layer **212** in a location corresponding to (e.g., overlapping or vertically aligned with at least a portion of) the channel area **212c** of the active layer **212** with a first insulating layer **13** that is an insulation film formed (e.g., positioned or deposited) between the gate electrode **215** and the active layer **212**. The gate electrode **215** may have a single layer structure or a multilayer structure including one or more metal materials selected from the group consisting of aluminum (Al), platinum (Pt), palladium (Pd), silver (Ag), magnesium (Mg), gold (Au), nickel (Ni), neodymium (Nd), iridium (Ir), chromium (Cr), lithium (Li), calcium (Ca), molybdenum (Mo), titanium (Ti), tungsten (W), and copper (Cu).

[0053] A source electrode **217a** and a drain electrode **217b** that are respectively coupled to the source region **212a** and the drain region **212b** of the active layer **212** are provided on the gate electrode **215** with a second insulating layer **16** that is an interlayer insulating film between the source and drain electrodes **217a** and **217b** and the gate electrode **215**. Each of the source electrode **217a** and the drain electrode **217b** may have a structure of two or more heterogeneous metal layers having different electron mobility. For example, each of the source electrode **217a** and the drain electrode **217b** may have a two or more layer structure including a metal material selected from the group consisting of Al, Pt, Pd, Ag, Mg, Au, Ni, Nd, Ir, Cr, Li, Ca, Mo, Ti, W, Cu, and alloys of these metal materials.

[0054] A third insulating layer **19** is provided on the second insulating layer **16** to cover the source electrode **217a** and the drain electrode **217b**.

[0055] The first insulating layer **13** and the second insulating layer **16** may include single layer inorganic insulating films or multilayer inorganic insulating films. The inorganic insulating films forming the first insulating layer **13** and the second insulating layer **16** may include a suitable insulating material such as SiO₂, SiNx, SiON, Al₂O₃, TiO₂, Ta₂O₅, HfO₂, ZrO₂, BST, or PZT, and the like.

[0056] The third insulating layer **19** may include an organic insulating film. The third insulating layer **19** may include general-purpose polymers (e.g., PMMA, PS), polymer derivatives having a phenol group, acrylic polymers, imide based polymers, arylether based polymers, amide based polymers, fluorinate polymers, p-xylene based polymers, vinyl alcohol based polymers, or suitable blends of these or similar materials.

[0057] A fourth insulating layer **20** is provided on the third insulating layer **19**. The fourth insulating layer **20** may include an organic insulating film. The fourth insulating layer **20** may include general-purpose polymers (PMMA, PS), polymer derivatives having a phenol group, acrylic polymers, imide based polymers, arylether based polymers, amide based polymers, fluorinate polymers, p-xylene based polymers, vinyl alcohol based polymers, or suitable blends of these or similar materials.

[0058] A pixel electrode **120** provided on the buffer layer **11** and the first insulating layer **13** is included in the pixel area PXL1.

[0059] The pixel electrode **120** is positioned in an opening C5 formed in the third insulating layer **19**.

[0060] The opening C5 formed in the third insulating layer **19** is greater than an opening C8 formed in the fourth insulating layer **20** and is smaller than an opening C1 formed in the second insulating layer **16**. The opening C1 formed in the second insulating layer **16**, the opening C5 formed in the third

insulating layer **19**, and the opening C8 formed in the fourth insulating layer **20** overlap with each other.

[0061] An end portion of the pixel electrode **120** is located on a top end of the opening C5 formed in the third insulating layer **19** and covered by the fourth insulating layer **20**. Meanwhile, a top surface of the pixel electrode **120** located in the opening C5 formed in the third insulating layer **19** is exposed to the opening C8 formed in the fourth insulating layer **20**.

[0062] The pixel electrode **120** includes a transfective metal (e.g., electrically conductive) layer **120b**. The pixel electrode **120** may further include layers **120a** and **120c** that are respectively formed in lower and upper portions of the transfective metal layer **120b** and include the transparent conductive oxide protecting the transfective metal layer **120b**.

[0063] The transfective metal layer **120b** may include silver (Ag) or a silver alloy. The transfective metal layer **120b** forms a micro cavity structure, along with an opposing electrode **122** that is a reflective electrode that will be described later, thereby increasing or improving light efficiency of the organic light-emitting display apparatus **1**.

[0064] The layers **120a** and **120c** including the transparent conductive oxide may include at least one selected from the group consisting of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In₂O₃), indium gallium oxide (IGO), and aluminum zinc oxide (AZO). The layer **120a** formed in the lower portion of the transfective metal layer **120b** and including the transparent conductive oxide may reinforce adhesion between the transparent protection layer **119** and the pixel electrode **120**. The layer **120c** formed in the upper portion of the transfective metal layer **120b** and including the transparent conductive oxide may function as a barrier layer protecting the transfective metal layer **120b**.

[0065] Meanwhile, if electrons are supplied to metal having a strong reduction like silver (Ag) forming the transfective metal layer **120b** during an etching process for patterning the pixel electrode **120**, silver (Ag) ions present in an etchant in an ion state may be problematically educed as silver (Ag) again. Such educed silver (Ag) may be a particle related defect factor causing a dark spot during a subsequent process of forming the pixel electrode **120**.

[0066] When the source electrode **217a** or the drain electrode **217b**, the first contact layer **117** of the pixel electrode contact unit PECNT1, the first pad layer **417** of a pad electrode, or a data wiring (not shown) formed of the same material as the materials of these is exposed to the etchant during a process of etching the pixel electrode **120** including silver (Ag), silver (Ag) ions having a strong reduction may be educed as silver (Ag) again by receiving electrons from these metal materials. For example, when these metal materials include molybdenum or aluminum, silver (Ag) may be educed again by providing electrons received from molybdenum or aluminum to silver (Ag) ions again. Educated silver (Ag) particles may cause particle related defects in the display, such as dark spots.

[0067] However, the source electrode **217a** or the drain electrode **217b** of the organic light-emitting display apparatus **1** according to the present embodiment is covered by the third insulating layer **19** that is the organic film, and thus the source electrode **217a** or the drain electrode **217b** is not exposed to the etchant including silver (Ag) ions during the process of etching the pixel electrode **120** including silver (Ag), thereby preventing a particle related defect due to the education of silver (Ag).

[0068] The transparent protection layer 119 is positioned between the pixel electrode 120 and the first insulating layer 13.

[0069] The transparent protection layer 119 is formed of the same material as those of a second pad layer 418 and a second contact layer 118 of the pixel electrode contact unit PECNT1. The transparent protection layer 119 may be formed of a transparent conductive oxide including at least one selected from the group consisting of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In_2O_3), indium gallium oxide (IGO), and aluminum zinc oxide (AZO).

[0070] The semi-transmissive metal layer 120b of the pixel electrode 120 including silver (Ag) may react with a material of the first insulating layer 13 located in a lower portion of the pixel electrode 120. Although the layer 120a is formed in a lower portion of the semi-transmissive metal layer 120b of the pixel electrode 120, the semi-transmissive metal layer 120b has a very small thickness of about 70 Å, the layer 120a does not entirely protect the semi-transmissive metal layer 120b.

[0071] For example, when the first insulating layer 13 used as the gate insulating film has a multiple-layer (e.g., double or two-layer) structure in which a silicon oxide film and a silicon nitride film are sequentially stacked from the buffer layer 11 to the transparent protection layer 119, the silicon nitride film provided on the first insulating layer 13 may be oxidized due to various factors, and thus the silicon oxide film is formed on a surface of the silicon nitride film.

[0072] If the transparent protection layer 119 is not formed between the pixel electrode 120 and the first insulating layer 13, silver (Ag) included in the transfective metal layer 120b reacts with the silicon oxide film formed on the surface of the silicon nitride film and diffuses through a pin hole of the layer 120a formed to be thin in the lower portion of the transfective metal layer 120b. Thus, a void may be generated in the transfective metal layer 120b, and the diffused silver (Ag) may cause a dark spot defect.

[0073] However, according to the embodiment of the present invention, because the transparent protection layer 119 is formed between the pixel electrode 120 and the first insulating layer 13, although a material that relatively easily reacts with silver (Ag) is formed on the first insulating layer 13, the transparent protection layer 119 may be blocked. Thus, a reactivity of silver (Ag) particles is controlled, thereby remarkably improving or reducing the occurrence of dark spot defects due to silver (Ag) particles.

[0074] FIG. 4 is a graph illustrating a number of dark spot defects of an organic light-emitting display apparatus before and after the transparent protection layer 119 is applied under the same condition according to an embodiment of the present invention.

[0075] Referring to FIG. 4, an average number of dark spot defects before the transparent protection layer 119 is applied may be, for example, 86, whereas the average number of dark spot defects after the transparent protection layer 119 is applied may be, for example, 17, which shows a considerable reduction in the number of dark spot defects.

[0076] Meanwhile, the transparent protection layer 119 of the present embodiment may increase the light efficiency of the organic light-emitting display apparatus 1 as well as reduce the dark spot defect.

[0077] FIG. 5 is a graph illustrating a relationship between a y color coordinate and efficiency of a blue emission layer with respect to a thickness of a transparent protection layer.

[0078] In more detail, FIG. 5 shows the relationship between the y color coordinate and efficiency of the blue emission layer when ① there is a structure having no transparent protection layer (reference), ② a thickness of the transparent protection layer 119 is 150 Å, ③ the thickness of the transparent protection layer 119 is 300 Å, and ④ the thickness of the transparent protection layer 119 is 370 Å. In this regard, a transparent conductive layer uses ITO (in cases of ①-④), ITO having a thickness of 70 Å is used as the layer 120a formed in the lower portion of the transfective metal layer 120b).

[0079] As shown in the graph of FIG. 5, the greater the thickness of ITO, the broader the range of the color coordinate that may be selected with respect to the reference and the higher the efficiency. Meanwhile, although not shown in the graph, when the thickness of ITO is equal to or greater than 800 Å, the range of the color coordinate is reduced, and the efficiency no longer increases. Thus, in terms of a function of blocking the reactivity of silver (Ag) of the transparent protection layer 119 and an improvement in the light characteristics of the transparent protection layer 119, in one embodiment the thickness of the transparent protection layer 119 may be formed in the range of 200 Å and 800 Å.

[0080] The pixel electrode 120 is coupled to the pixel contact unit PECNT1 through a contact hole C6 formed in the third insulating layer 19. The pixel contact unit PECNT1 is electrically coupled to one of a source electrode and a drain electrode of a driving transistor and drives the pixel electrode 120.

[0081] The pixel contact unit PECNT1 may include a first contact layer 117 including the same material as the above-described material of the source electrode 217a and the drain electrode 217b, a second contact layer 118 including a transparent conductive oxide, a third contact layer 114 including the transparent conductive oxide, and a fourth contact layer 115a including the same material as that of the gate electrode 215.

[0082] That is, according to one embodiment, when the pixel electrode 120 and a driving device are electrically coupled to each other through the contact hole C6 formed in the third insulating layer 19, by way of the first contact layer 117 and the second contact layer 118, because a thickness of the pixel electrode 120 that is used as a semi-transmissive metal layer may be relatively small or thin, a stable connection through an etching surface of the third insulating layer 19 or the contact hole C6 may be relatively difficult to obtain. However, according to the present embodiment, even if the connection through the contact hole C6 formed in the third insulating layer 19 fails, because the pixel electrode 120 directly contacts the third contact layer 114 on a floor portion of the opening C5, a signal may be received from the driving device normally.

[0083] Meanwhile, although not shown in detail in FIG. 2, the first contact layer 117 is coupled to a data line (not shown) that may be electrically coupled to one of the source electrode and the drain electrode of the driving transistor. If a transistor of FIG. 2 is the driving transistor, the first contact layer 117 may be directly coupled to the source electrode 217a or the drain electrode 217b.

[0084] An intermediate layer including the organic emission layer 121 is provided on the pixel electrode 120 with the top surface exposed in the opening C8, which is formed in (e.g., through) the fourth insulating layer 20. The organic emission layer 121 may be formed of a low molecular weight

organic material or a high molecular weight organic material. When the organic emission layer **121** is formed of the low molecular weight organic material, a hole transport layer (HTL), a hole injection layer (HIL), an electron transport layer (ETL), and an electron injection layer (EIL) may be stacked with respect to the organic emission layer **121**. Various other layers may be stacked if necessary. In this case, various low molecular weight organic materials may be used including copper phthalocyanine (CuPc), N'-diphenyl-benzidine (NPB), and tris-8-hydroxyquinoline aluminum (Alq3). When the organic emission layer **121** is formed of the high molecular weight organic material, the HTL may be used in addition to the organic emission layer **121**. The HTL may be formed of poly-(3,4)-ethylene-dihydroxy thiophene (PEDOT) or polyaniline (PANI). In this case, a high molecular weight organic material may include a polyphenylene vinylene (PPV)-based high molecular weight organic material and a polyfluorene-based high molecular weight organic material. An inorganic material may be further provided between the pixel electrode **120**, and the opposing electrode **122**.

[0085] Although the organic emission layer **121** is positioned only on a floor of the opening **C8** in FIG. **2**, this is for convenience of description and the present invention is not limited thereto. In one embodiment, the organic emission layer **121** is formed on a top surface of the fourth insulating layer **20**, along an etching surface of the opening **C5** formed in the third insulating layer **19**, as well as on the floor of the opening **C8**.

[0086] The opposing electrode **122** is provided on the organic emission layer **121** as a common electrode. The organic light-emitting display apparatus **1** according to the present embodiment uses the pixel electrode **120** as an anode and the opposing electrode **122** as a cathode. Polarities of the electrodes may be switched.

[0087] The opposing electrode **122** may be configured as a reflective electrode including a reflective material. In this regard, the opposing electrode **122** may include one or more materials selected from the group consisting of Al, Mg, Li, Ca, LiF/Ca, and LiF/Al. The opposing electrode **122** is configured as the reflective electrode, so that light emitted from the organic emission layer **121** is reflected from the opposing electrode **121**, is transmitted through the pixel electrode **120** (formed of, e.g., semi-transmissive metal), and is emitted to the substrate **10**.

[0088] An organic light-emitting display apparatus to which the present invention is applied is a bottom emission light-emitting display apparatus in which light is emitted from the organic emission layer **121** toward the substrate **10** to form an image. Thus, the opposing electrode **122** is configured as a reflective electrode.

[0089] A capacitor including a first electrode **312** positioned on the same layer as (e.g., at least partially coplanar with) the active layer **212**, a second electrode **314** positioned on the same layer as (e.g., at least partially coplanar with) the gate electrode **215**, and a third electrode **317** positioned on the same layer as (e.g., at least partially coplanar with) the source electrode **217a** and the drain electrode **217b** is provided in the capacitor area **CAP1** and on the substrate **10** and the buffer layer **11**.

[0090] The first electrode **312** of the capacitor may be formed as a semiconductor doped with ion impurities, like the source area **212a** and the drain area **212b** of the active layer **212**.

[0091] The second electrode **314** of the capacitor is positioned on the first insulating layer **13** in the same way as the gate electrode **215**, whereas materials of the second electrode **314** and the gate electrode **215** may be different from each other. The material of the second electrode **314** may include the transparent conductive oxide. The semiconductor doped with ion impurities is formed on the first electrode **312** through the second electrode **314**, thereby forming the capacitor having a metal-insulator-metal (MIM) structure.

[0092] The third electrode **317** of the capacitor may be formed of the same material as those of the source electrode **217a** and the drain electrode **217b**. As described above, the third electrode **317** is covered by the third insulating layer **19** that is the organic film, and thus the third electrode **317** is not exposed to the etchant including silver (Ag) ions during the process of etching the pixel electrode **120** including silver (Ag), thereby preventing the particle related defect due to the eduction of silver (Ag).

[0093] The capacitor constitutes a parallel circuit including the first electrode **312**, the second electrode **314**, and a third circuit, thereby increasing a capacitance of the organic light-emitting display apparatus **1** without increasing an area of the capacitor. Thus, the area of the capacitor may be reduced by the increase in the capacitance, thereby increasing an aperture ratio.

[0094] The pad area **PAD1** is an area in which pad electrodes **417** and **418** are located or positioned outside the display area **DA** as connection terminals for an external driver.

[0095] The first pad layer **417** may have a structure of a plurality of metal layers having different electron mobility like the above-described source electrode **217a** and drain electrode **217b**. For example, the first pad layer **417** may have a multilayer structure including one or more metal materials selected from the group consisting of aluminum (Al), platinum (Pt), palladium (Pd), silver (Ag), magnesium (Mg), gold (Au), nickel (Ni), neodymium (Nd), iridium (Ir), chromium (Cr), lithium (Li), calcium (Ca), molybdenum (Mo), titanium (Ti), tungsten (W), and copper (Cu).

[0096] The second pad layer **418** may be formed of a transparent conductive oxide including at least one selected from the group consisting of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In₂O₃), indium gallium oxide (IGO), and aluminum zinc oxide (AZO). The first pad layer **417** may prevent pad electrodes from being exposed to moisture and oxygen, thereby preventing the deterioration of reliability of the pad electrodes.

[0097] As described above, although the first pad layer **417** is located in an area exposed to the contact hole **C7** formed in the third insulating layer **19**, because the second pad layer **418** that is a protection layer is formed on an upper portion of the first pad layer **417**, the first pad layer **417** is not (or substantially not) exposed to the etchant during the process of etching the pixel electrode **120**.

[0098] Moreover, an end portion (or peripheral area) of the first pad layer **417** that is sensitive to an external environment such as moisture or oxygen is covered by the third insulating layer **19**, and thus the end portion (or peripheral area) of the first pad layer **417** is not also exposed to the etchant during the process of etching the pixel electrode **120**.

[0099] Therefore, the particle related defect due to the eduction of silver (Ag) may be prevented, and the deterioration of reliability of the pad electrodes may also be prevented.

[0100] Meanwhile, although not shown in FIG. 2, the organic light-emitting display apparatus 1 according to the present embodiment may further include a sealing member that seals the display area DA including the pixel area PXL1, the capacitor area CAP1, and the transistor area TR1. The sealing member may be formed as a sealing thin film formed by alternating a substrate including a glass member, a metal film, or an organic insulating film, and an inorganic insulating film.

[0101] A method of manufacturing the organic light-emitting display apparatus 1 according to the present embodiment will now be described with reference to FIGS. 3A through 3I below.

[0102] FIGS. 3A through 3I are schematic cross-sectional views illustrating a method of manufacturing the organic light-emitting display apparatus 1, according to an embodiment of the present invention.

[0103] FIG. 3A is a schematic cross-sectional view illustrating a first mask process of the organic light-emitting display apparatus 1 according to the present embodiment of the present invention.

[0104] Referring to FIG. 3A, the buffer layer 11 is formed on the substrate 10 and a semiconductor layer is formed on the buffer layer 11 and patterned to form the active layer 212 of a thin film transistor and the first electrode 312 of a capacitor.

[0105] Although not shown in FIG. 3A, a photoresist (not shown) is coated on the semiconductor layer, the semiconductor layer is patterned by using photolithography using a first photomask (not shown), and the active layer 212 and the first electrode 312 are formed. A first masking process using photolithography includes performing exposure using an exposure device (not shown) on the first mask (not shown), and performing a series of processes, such as developing, etching, stripping, and ashing.

[0106] The semiconductor layer (not shown) may include amorphous silicon or crystalline silicon. In this regard, crystalline silicon may be formed by crystallizing amorphous silicon. Amorphous silicon may be crystallized by using various methods such as rapid thermal annealing (RTA), solid phase crystallization (SPC), excimer laser annealing (ELA), metal-induced crystallization (MIC), metal-induced lateral crystallization (MILC), sequential lateral solidification (SLS), and the like. The semiconductor layer is not limited to amorphous silicon or crystalline silicon and may include an oxide semiconductor or other suitable semiconductor material.

[0107] FIG. 3B is a schematic cross-sectional view illustrating a second mask process of the organic light-emitting display apparatus 1 according to the present embodiment of the present invention.

[0108] The first insulating layer 13 is formed on a resultant structure of the first mask process of FIG. 3A, a transparent conductive oxide layer (not shown) is formed on the first insulating layer 13 and then patterned.

[0109] As a result of the patterning, the third contact layer 114 of the pixel electrode contact unit PECNT1 and the second electrode 314 of the capacitor are formed on the first insulating layer 13.

[0110] FIG. 3C is a schematic cross-sectional view for illustrating a third mask process of the organic light-emitting display apparatus 1 according to the present embodiment of the present invention.

[0111] A first metal (e.g., electrically conductive) layer is deposited on a resultant structure of the second mask process

of FIG. 3B and then patterned. In this regard, as described above, the first metal layer (not shown) may be a single layer or a multilayer formed of one or more metal materials selected from the group consisting of aluminum (Al), platinum (Pt), palladium (Pd), silver (Ag), magnesium (Mg), gold (Au), nickel (Ni), neodymium (Nd), iridium (Ir), chromium (Cr), lithium (Li), calcium (Ca), molybdenum (Mo), titanium (Ti), tungsten (W), and copper (Cu).

[0112] As a result of the patterning, the gate electrode 215 and a gate metal layer 115 covering the third contact layer 114 are formed on the first insulating layer 13.

[0113] The above-described structure is doped with ion impurities. The active layer 212 of the thin film transistor and the first electrode 312 of the capacitor are doped with ion impurities B or P at a concentration of 1×10^{15} atoms/cm² or more.

[0114] The active layer 212 is doped with ion impurities by using the gate electrode 215 as a self-aligning mask, and thus the active layer 212 includes the source area 212a and the drain area 212b doped with ion impurities and the channel area 212c positioned between the source area 212a and the drain area 212b. In this regard, the first electrode 312 of the capacitor is an electrode doped with ion impurities and forming a MIM CAP.

[0115] Therefore, the first electrode 312 of the capacitor as well as the active layer 212 are simultaneously or concurrently doped by using a single doping process, thereby reducing manufacturing cost by reducing the complexity of the doping process.

[0116] FIG. 3D is a schematic cross-sectional view illustrating a fourth mask process of the organic light-emitting display apparatus 1 according to the present embodiment of the present invention.

[0117] Referring to FIG. 3D, the second insulating layer 16 is formed on a resultant structure of the third mask process of FIG. 3C and then patterned, and thus openings C3 and C4 exposing the source area 212a and the drain area 212b of the active layer 212 and an opening C1 are formed in an area spaced apart from a side of the active layer 212 as an area in which the pixel electrode 120 is to be located that will be described later.

[0118] FIG. 3E is a schematic cross-sectional view illustrating a fifth mask process of the organic light-emitting display apparatus 1 according to the present embodiment of the present invention.

[0119] Referring to FIG. 3E, a second metal (e.g., electrically conductive) layer is formed on a resultant structure of the fourth mask process of FIG. 3D and then patterned to form the source electrode 217a and the drain electrode 217b, the first contact layer 117 of the pixel electrode contact unit PECNT1, and the first pad layer 417 of a pad electrode.

[0120] The second metal layer may have a structure of two or more heterogeneous metal layers having different electron mobility. For example, the second metal layer may have a multiple (e.g., two or more) layer structure including a metal material selected from the group consisting of aluminum (Al), platinum (Pt), palladium (Pd), silver (Ag), magnesium (Mg), gold (Au), nickel (Ni), neodymium (Nd), iridium (Ir), chromium (Cr), lithium (Li), calcium (Ca), molybdenum (Mo), titanium (Ti), tungsten (W), copper (Cu), and alloys of these metal materials.

[0121] A configuration of the first pad layer 417 is illustrated in detail for an exemplary illustration of a configuration of the second metal layer. For example, the second metal layer

of the present embodiment may include a first layer **417a** including molybdenum (Mo), a second layer **417b** including aluminum (Al), and a third layer **417c** including molybdenum (Mo).

[0122] The second layer **417b** including aluminum (Al) is a metal layer having a small resistance and excellent electrical characteristic. The first layer **417a** located in a lower portion of the second layer **417b** and including molybdenum (Mo) reinforces adhesion between the second insulating layer **16** and the second layer **417b**. The third layer **417c** located in an upper portion of the second layer **417b** and including molybdenum (Mo) may function as a barrier layer preventing a heel lock of aluminum included in the second layer **417b**, oxidation, and diffusion.

[0123] Meanwhile, although not shown in FIG. 3E, a data wiring may also be formed by patterning the second metal layer during the fifth mask process.

[0124] FIG. 3F is a schematic cross-sectional view illustrating a sixth mask process of the organic light-emitting display apparatus **1** according to the present embodiment of the present invention.

[0125] Referring to FIG. 3F, a transparent conductive oxide layer is formed on a resultant structure of the fifth mask process of FIG. 3E and then patterned to form the second contact layer **118** of the pixel electrode contact unit PECNT1, the second pad layer **418** of the pad electrode, and the transparent protection layer **119**.

[0126] The transparent conductive oxide layer include at least one selected from the group consisting of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In_2O_3), indium gallium oxide (IGO), and aluminum zinc oxide (AZO).

[0127] FIG. 3G is a schematic cross-sectional view illustrating a seventh mask process of the organic light-emitting display apparatus **1** according to the present embodiment of the present invention.

[0128] Referring to FIG. 3G, the third insulating layer **19** is formed on a resultant structure of the sixth mask process of FIG. 3F and then patterned, and thus the contact hole **C6** exposing an upper portion of the second contact layer **118**, the contact hole **C7** exposing an upper portion of the second pad layer **418**, and the opening **C5** are formed in the pixel area PXL1 in which the pixel electrode **120** is to be located that will be described later.

[0129] The third insulating layer **19** is formed to completely surround the source electrode **217a** and the drain electrode **217b** so as to prevent heterogeneous wirings having different electric potentials from contacting an etchant in which silver (Ag) ions are dissolved during a process of etching the pixel electrode **120** including silver (Ag) that will be described later.

[0130] The third insulating layer **19** may include an organic insulating film to function as a planarizing film. The organic insulating film may use general-purpose polymers (e.g., PMMA or PS), polymer derivatives having a phenol group, acrylic polymers, imide based polymers, arylether based polymers, amide based polymers, fluorinate polymers, p-xylylene based polymers, vinyl alcohol based polymers, or suitable blends of these or other suitable insulating materials.

[0131] The opening **C5** formed in the third insulating layer **19** and the opening **C1** formed in the second insulating layer **16** overlap with each other while the opening **C5** formed in the third insulating layer **19** is smaller than the opening **C1** formed in the second insulating layer **16**.

[0132] FIG. 3H is a schematic cross-sectional view illustrating an eighth mask process of the organic light-emitting display apparatus **1** according to the present embodiment of the present invention.

[0133] Referring to FIG. 3H, a semitransparent metal (e.g., electrically conductive) layer is formed on a resultant structure of the seventh mask process of FIG. 3G and then patterned to form the pixel electrode **120**.

[0134] The pixel electrode **120** is coupled to a driving transistor through the pixel electrode contact unit PEDOT1 and located in the opening **C5** formed in the third insulating layer **19**.

[0135] The pixel electrode **120** includes the transfective metal layer **120b**. The pixel electrode **120** may include the layers **120a** and **120c** that are respectively formed at lower and upper sides or surfaces of the transfective metal layer **120b** and include the transparent conductive oxide protecting the transfective metal layer **120b**.

[0136] The transfective metal layer **120b** may be formed of silver (Ag) or a silver alloy. The layers **120a** and **120c** including the transparent conductive oxide may include at least one selected from the group consisting of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In_2O_3), indium gallium oxide (IGO), and aluminum zinc oxide (AZO). The transfective metal layer **120b** forms a micro cavity structure, along with the opposing electrode **122** that is a reflective electrode that will be described later, thereby increasing light efficiency of the organic light-emitting display apparatus **1**.

[0137] Meanwhile, if electrons are supplied to electrically conductive materials (e.g., metal) having a strong reduction like silver (Ag) during an etching process for patterning the pixel electrode **120**, silver (Ag) ions present in an etchant in an ion state may be problematically reduced as silver (Ag) again. If the source electrode **217a** or the drain electrode **217b**, the first contact layer **117** of the pixel electrode contact unit PECNT1, the first pad layer **417** of a pad electrode, or a data wiring (not shown) formed of the same material as the materials of these is exposed to the etchant during a process of etching the pixel electrode **120** including silver (Ag), silver (Ag) ions having a strong reduction may be reduced as silver (Ag) again by receiving electrons from these metal materials.

[0138] However, the source electrode **217a** or the drain electrode **217b** according to the present embodiment is patterned before the eighth mask process of patterning the pixel electrode **120** and is covered by the third insulating layer **19** that is the organic film. Accordingly, the source electrode **217a** or the drain electrode **217b** is not exposed to the etchant including silver (Ag) ions during the process of etching the pixel electrode **120** including silver (Ag), thereby preventing or reducing a particle related defect due to the reduction of silver (Ag).

[0139] Although the first contact layer **117** of the pixel electrode contact unit PECNT1 and the first pad layer **417** according to the present embodiment are respectively positioned in areas exposed by the contact holes **C6** and **C7** formed in the third insulating layer **19**, because the second contact layer **118** of the pixel electrode contact unit PECNT1 and the second pad layer **418** that are protection layers are respectively formed on the first contact layer **117** of the pixel electrode contact unit PECNT1 and the first pad layer **417**, the first contact layer **117** of the pixel electrode contact unit PECNT1 and the first pad layer **417** are not exposed to the etchant during the process of etching the pixel electrode

(120), thereby preventing or reducing a particle related defect due to the eduction of silver (Ag).

[0140] If the transparent protection layer 119 is not formed between the pixel electrode 120 and the first insulating layer 13, silver (Ag) included in the transfective metal layer 120b reacts with a silicon oxide film formed on a surface of a silicon nitride film and diffuses through a pin hole of the layer 120a formed to be thin in the lower portion of the transfective metal layer 120b. Thus, a void is generated in the transfective metal layer 120b, and the diffused silver (Ag) may cause a dark spot defect.

[0141] However, according to the embodiment of the present invention, because the transparent protection layer 119 is formed between the pixel electrode 120 and the first insulating layer 13, although a Material that easily reacts with silver (Ag) is formed on the first insulating layer 13, the transparent protection layer 119 may be blocked. Thus, a reactivity of silver (Ag) particles is controlled, thereby remarkably improving the dark spot defect due to silver (Ag) particles.

[0142] FIG. 3I is a schematic cross-sectional view illustrating a ninth mask process of the organic light-emitting display apparatus 1 according to the present embodiment of the present invention.

[0143] Referring to FIG. 3I, the fourth insulating layer 20 is formed on a resultant structure of the eighth mask process of FIG. 3H, and then the ninth mask process of forming the opening C8 exposing an upper portion of the pixel electrode 120 is performed.

[0144] The fourth insulating layer 20 functions as a pixel defining layer and may include an organic insulating film including general-purpose polymers (e.g., PMMA, PS), polymer derivatives having a phenol group, acrylic polymers, imide based polymers, aryether based polymers, amide based polymers, fluorinate polymers, p-xylene based polymers, vinyl alcohol based polymers, or suitable blends of these or other suitable insulating materials.

[0145] An intermediate layer (not shown) including the organic emission layer 121 of FIG. 2 is formed on a resultant structure of the eighth mask process of FIG. 3H, and the opposing electrode 122 of FIG. 2 is formed.

[0146] According to the above-described organic light-emitting display apparatus 1 and method of manufacturing the organic light-emitting display apparatus 1, the pixel electrode 120 includes the semi-transmissive metal layer 120b, thereby increasing light efficiency of the organic light-emitting display apparatus 1 by a micro-cavity.

[0147] The source electrode 217a or the drain electrode 217b is covered by the third insulating layer 19 that is the organic film, and thus the source electrode 217a or the drain electrode 217b is not exposed to the etchant including silver (Ag) ions, thereby preventing the particle related defect due to the eduction of silver (Ag).

[0148] The second contact layer 118 of the pixel electrode contact unit PECNT1 and the second pad layer 418 that are protection layers are respectively formed on the first contact layer 117 of the pixel electrode contact unit PECNT1 and the first pad layer 417, and thus the first contact layer 117 of the pixel electrode contact unit PECNT1 and the first pad layer 417 are not exposed to the etchant during the process of etching the pixel electrode (120), thereby preventing the particle related defect due to the eduction of silver (Ag).

[0149] Further, because the transparent protection layer 119 is formed in a lower portion of the pixel electrode 120,

although a material that easily reacts with silver (Ag) is formed on the first insulating layer 13, the transparent protection layer 119 may be blocked. Thus, a reactivity of silver (Ag) particles is controlled, thereby remarkably improving the dark spot defect due to silver (Ag) particles.

[0150] An organic light-emitting display apparatus 2 according to a comparison example will now be described with reference to FIG. 6 below.

[0151] The same reference numerals denote the same elements below. Differences between the organic light-emitting display apparatus 1 according to the previous embodiment and the organic light-emitting display apparatus 2 according to the comparison example will now be described.

[0152] Referring to FIG. 6, a pixel area PXL2 including the at least one organic emission layer 121, a transistor area TR2 including at least one thin film transistor, a capacitor area CAP2 including at least one capacitor, and a pad area PAD2 are provided on the substrate 10.

[0153] The transistor area TR2, the capacitor area CAP2, and the pad area PAD2 of the organic light-emitting display apparatus 2 according to the comparison example have similar configurations as those of the organic light-emitting display apparatus 1 according to the previous embodiment, except for the pixel area PXL2.

[0154] The pixel area PXL2 according to the comparison example does not include the transparent protection layer 119 of FIG. 2 between the pixel electrode 120 and the first insulating layer 13.

[0155] The pixel electrode 120 includes the transfective metal layer 120b and the layers 120a and 120c that are respectively formed in lower and upper portions of the transfective metal layer 120b and include the transparent conductive oxide protecting the transfective metal layer 120b.

[0156] The layer 120a formed in the lower portion of the semi-transmissive metal layer 120b has a very small thickness of about 70 Å, and thus the layer 120a may not entirely protect the semi-transmissive metal layer 120b.

[0157] For example, when the first insulating layer 13 used as the gate insulating film has a double structure in which a silicon oxide film 13-1 and a silicon nitride film 13-2 are sequentially stacked from the buffer layer 11 to the transparent protection layer 119, a silicon nitride film 13a provided on the first insulating layer 13 may be oxidized due to various factors, and thus the silicon oxide film 13a is formed on a surface of the silicon nitride film 13-2.

[0158] The transparent protection layer 119 is not formed between the pixel electrode 120 and the first insulating layer 13, and thus silver (Ag) included in the transfective metal layer 120b may react with the silicon oxide film formed on the surface of the silicon nitride film and diffuse through a pin hole of the layer 120a formed to be thin in the lower portion of the transfective metal layer 120b. Thus, a void may be generated in the transfective metal layer 120b, and the diffused silver (Ag) may cause a dark spot defect.

[0159] For example, when the first insulating layer 13 used as a gate insulating film has a multiple layer structure in which the silicon oxide film 13-1 and the silicon nitride film 13-2 are sequentially stacked from the buffer layer 11 to the transparent protection layer 119, the silicon nitride film 13-2 provided on the first insulating layer 13 may be oxidized. In this regard, the silicon oxide film 13a may be formed on a surface of the silicon nitride film 13-2.

[0160] The silicon oxide film 13a causes to generate a pin hole in the layer 120c formed to be thin in the upper portion of

the transfective metal layer **120b** formed in a subsequent process. Silver (Ag) particles included in the transfective metal layer **120b** react with the silicon oxide film **13a** and agglomerate through the pin hole, and thus a void is generated in the transfective metal layer **120b** and causes a dark spot defect.

[0161] A method of manufacturing the organic light-emitting display apparatus **2** will now be described with reference to FIGS. 7A through 7I below.

[0162] FIG. 7A is a schematic cross-sectional view illustrating a first mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0163] The active layer **212** of a thin film transistor and the first electrode **312** of a capacitor are formed on the substrate **10**.

[0164] FIG. 7B is a schematic cross-sectional view illustrating a second mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0165] The third contact layer **114** of a cathode electrode contact unit and the second electrode **314** of the capacitor are formed on the first insulating layer **13**.

[0166] FIG. 7C is a schematic cross-sectional view illustrating a third mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0167] The gate electrode **215** and a gate metal layer **115** covering the third contact layer **114** are formed on the first insulating layer **13**.

[0168] FIG. 7D is a schematic cross-sectional view illustrating a fourth mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0169] Openings **C3** and **C4** exposing the source area **212a** and the drain area **212b** of the active layer **212** and the opening **C1** are formed in an area spaced apart from a side of the active layer **212** as an area in which the pixel electrode **120** is to be located.

[0170] FIG. 7E is a schematic cross-sectional view illustrating a fifth mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0171] Referring to FIG. 7E, a second metal (e.g., electrically conductive) layer is formed on a resultant structure of the fourth mask process of FIG. 7D and then patterned to form the source electrode **217a** and the drain electrode **217b**, the first contact layer **117** of a pixel electrode contact unit, and the first pad layer **417** of a pad electrode.

[0172] During a process of patterning the second metal layer, the gate metal layer **115** formed in the first insulating layer **13** of the opening **C1** is etched and removed. During a process of removing the gate insulating layer **13**, the first insulating layer **13** may deteriorate. For example, when the first insulating layer **13** used as a gate insulating film has a double structure in which the silicon oxide film **13-1** and the silicon nitride film **13-2** are sequentially stacked from the buffer layer **11** to the transparent protection layer **119**, the silicon nitride film **13-2** provided on the first insulating layer **13** may be oxidized. In this regard, the silicon oxide film **13a** may be formed on a surface of the silicon nitride film **13-2**. The silicon oxide film **13a** may also be formed on a surface of the first insulating layer **13** by another processing factor during the second through fourth mask processes.

[0173] FIG. 7F is a schematic cross-sectional view illustrating a sixth mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0174] Referring to FIG. 7F, a transparent conductive oxide layer is formed on a resultant structure of the fifth mask

process of FIG. 7E and then patterned to form the second contact layer **118** of the pixel electrode contact unit and the second pad layer **418** of the pad electrode.

[0175] FIG. 7G is a schematic cross-sectional view illustrating a seventh mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0176] Referring to FIG. 7G, the third insulating layer **19** is formed on a resultant structure of the sixth mask process of FIG. 7F and then patterned, and thus the contact hole **C6** exposing an upper portion of the second contact layer **118** of the pixel electrode contact unit, the contact hole **C7** exposing an upper portion of the second pad layer **418**, and the opening **C5** are formed in the pixel area PXL1 in which the pixel electrode **120** is to be located.

[0177] The third insulating layer **19** that remains after being patterned by asking (or other suitable patterning technique) is removed during a process of patterning the third insulating layer **19** formed as the organic insulating film. In this regard, the silicon oxide film **13a** may be formed on a surface of the first insulating layer **13** or may further deteriorate.

[0178] FIG. 7H is a schematic cross-sectional view illustrating an eighth mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0179] Referring to FIG. 7H, a semi-transmissive metal (e.g., electrically conductive) layer is formed on a resultant structure of the seventh mask process of FIG. 7G and then patterned to form the pixel electrode **120**.

[0180] The pixel electrode **120** includes the transfective metal layer **120b** and the layers **120a** and **120c** that are respectively formed in lower and upper portions of the transfective metal layer **120b** and include the transparent conductive oxide protecting the transfective metal layer **120b**.

[0181] The transparent protection layer **119** of the previous embodiment is not formed between the pixel electrode **120** and the first insulating layer **13**, and thus silver (Ag) included in the transfective metal layer **120b** reacts with the silicon oxide film **13a** formed on a surface of the silicon nitride film **13-2** and diffuses through a pin hole of the layer **120a** formed to be thin in the lower portion of the transfective metal layer **120b**. Thus, a void may be generated in the transfective metal layer **120b**, and the diffused silver (Ag) may cause a dark spot defect.

[0182] FIG. 7I is a schematic cross-sectional view illustrating a ninth mask process of the organic light-emitting display apparatus **2** according to the comparison example.

[0183] Referring to FIG. 7I, the fourth insulating layer **20** is formed on a resultant structure of the eighth mask process of FIG. 7H, and then the ninth mask process of forming the opening **C8** exposing an upper portion of the pixel electrode **120** is performed.

[0184] An intermediate layer (not shown) including the organic emission layer **121** of FIG. 2 is formed on a resultant structure of the eighth mask process of FIG. 7H, and the opposing electrode **122** of FIG. 2 is formed.

[0185] In this regard, impurities may penetrate into the organic emission layer **121** due to the silver (Ag) void generated in the transfective metal layer **120b**, which may cause the dark spot defect.

[0186] As described above, the organic light-emitting display apparatus **2** according to the comparison example does not include the transparent protection layer **119** between the pixel electrode **120** and the first insulating layer **13**, which does not prevent a void from generating due to silver (Ag) of

the pixel electrode 120, and thus the dark spot defect occurs. Further, an increase in the light efficiency may not be expected.

[0187] As described above, the organic light-emitting display apparatus and method of manufacturing the same according to the present invention may have the following characteristics:

[0188] First, a pixel electrode is formed as a semi-transmissive metal layer, thereby increasing light efficiency of a display apparatus by a micro cavity.

[0189] Second, a source electrode and a drain electrode (including a data wire) are covered by a third insulation layer that is an organic film, thereby preventing silver (Ag) from being etched again due to the source electrode and the drain electrode when the pixel electrode is patterned.

[0190] Third, protection layers are formed on a first contact layer of a pixel electrode contact unit, a first contact layer of a cathode contact unit, and a top portion of a first pad layer of a pad electrode, thereby preventing silver (Ag) from being etched again due to the first contact layer and the first pad layer when the pixel electrode is patterned.

[0191] Fourth, a structure of the pixel electrode contact unit is dualized, thereby preventing a signal short circuit between the pixel electrode and a driving device.

[0192] Fifth, a protection layer including a transparent conductive oxide is formed in a lower portion of the pixel electrode including semi-transmissive metal, thereby reducing a dark spot defect due to silver (Ag) and increasing a light characteristic.

[0193] While the present invention has been particularly shown and described with reference to exemplary embodiments thereof, it will be understood by those of ordinary skill in the art that various changes in form and details may be made therein without departing from the spirit and scope of the present invention as defined by the following claims, and their equivalents.

What is claimed is:

1. An organic light-emitting display apparatus comprising:
 - a thin film transistor comprising an active layer, a gate electrode, a source electrode, a drain electrode, a first insulating layer between the active layer and the gate electrode, and a second insulating layer between the gate electrode and the source and drain electrodes;
 - a pad electrode comprising a first pad layer at a same layer as the source electrode and the drain electrode and a second pad layer on the first pad layer;
 - a third insulating layer covering the source electrode and the drain electrode and an end portion of the pad electrode;
 - a pixel electrode comprising a semi-transmissive electrically conductive layer in an opening in the third insulating layer;
 - a transparent protection layer between the pixel electrode and the first insulating layer;
 - a fourth insulating layer having an opening in a location corresponding to the opening formed in the third insulating layer, the fourth insulating layer covering the end portion of the pad electrode;
 - an emission layer on the pixel electrode; and
 - an opposing electrode on the emission layer.
2. The organic light-emitting display apparatus of claim 1, wherein the transparent protection layer comprises a same material as the second pad layer.

3. The organic light-emitting display apparatus of claim 1, wherein the second pad layer comprises a transparent conductive oxide.

4. The organic light-emitting display apparatus of claim 3, wherein the transparent protection layer comprises one or more selected from the group consisting of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), indium oxide (In_2O_3), indium gallium oxide (IGO), and aluminum zinc oxide (AZO).

5. The organic light-emitting display apparatus of claim 1, wherein a thickness of the transparent protection layer is in a range of 200 Å and 800 Å.

6. The organic light-emitting display apparatus of claim 1, wherein the source electrode and the drain electrode have a stack structure of a plurality of heterogeneous electrically conductive layers having different electron mobility.

7. The organic light-emitting display apparatus of claim 6, wherein the source electrode and the drain electrode comprise a layer comprising molybdenum and a layer comprising aluminum.

8. The organic light-emitting display apparatus of claim 1, further comprising: a capacitor comprising a first electrode at a same layer as the active layer and a second electrode at a same layer as the gate electrode.

9. The organic light-emitting display apparatus of claim 8, wherein the first electrode of the capacitor comprises a semiconductor material doped with ion impurities.

10. The organic light-emitting display apparatus of claim 8, wherein the second electrode of the capacitor comprises a transparent conductive oxide.

11. The organic light-emitting display apparatus of claim 8, wherein the capacitor further comprises a third electrode at a same layer as the source electrode and the drain electrode.

12. The organic light-emitting display apparatus of claim 8, further comprising: a pixel electrode contact unit electrically coupled between the pixel electrode and one of the source electrode and the drain electrode through a contact hole formed in the third insulating layer,

wherein the pixel electrode contact unit comprises:

- a first contact layer comprising a same material as the source electrode and the drain electrode;
- a second contact layer comprising a same material as the second pad layer; and
- a third contact layer in the first insulating layer and the second insulating layer and comprising a same material as the second electrode of the capacitor,

wherein the first contact layer is electrically coupled to the third contact layer through a contact hole formed in the second insulating layer.

13. The organic light-emitting display apparatus of claim 12, wherein an end portion of the third contact layer is on a top end of the opening formed in the third insulating layer.

14. The organic light-emitting display apparatus of claim 12, wherein an end portion of the third contact layer protrudes from an etching surface of an opening formed in the second insulating layer and directly contacts the pixel electrode.

15. The organic light-emitting display apparatus of claim 12, wherein an end portion of the third contact layer protrudes from an etching surface of an opening formed in the third insulating layer and directly contacts the pixel electrode.

16. The organic light-emitting display apparatus of claim 15, wherein the pixel electrode contact unit further comprises

a fourth contact layer between the first insulating layer and the third insulating layer and comprising a same material as the gate electrode.

17. The organic light-emitting display apparatus of claim **12**, wherein an end portion of the third contact layer protrudes from an etching surface of an opening formed in the third insulating layer and directly contacts the transparent protection layer.

18. The organic light-emitting display apparatus of claim **1**, wherein the first pad layer comprises a same material as the source electrode and the drain electrode.

19. The organic light-emitting display apparatus of claim **1**, wherein the semi-transmissive electrically conductive layer comprises silver (Ag) or a silver alloy.

20. The organic light-emitting display apparatus of claim **1**, wherein a protection layer is further stacked on at least one surface of the semi-transmissive electrically conductive layer.

21. The organic light-emitting display apparatus of claim **20**, wherein the protection layer comprises a transparent conductive oxide.

22. The organic light-emitting display apparatus of claim **1**, wherein an opening in the second insulating layer, the opening in the third insulating layer, and the opening in the fourth insulating layer overlap with each other, and wherein a width of the opening in the third insulating layer is greater than a width of the opening formed in the fourth insulating layer and smaller than a width of the opening formed in the second insulating layer.

23. The organic light-emitting display apparatus of claim **1**, wherein the opposing electrode comprises a reflective electrically conductive layer.

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摘要(译)

一种显示装置，包括：薄膜晶体管，包括位于有源层和栅电极之间的第一绝缘层，以及位于栅电极和源电极和漏电极之间的第二绝缘层；焊盘电极，包括第一焊盘层和第一焊盘层上的第二焊盘层；第三绝缘层，覆盖源电极和漏电极以及焊盘电极的端部；像素电极，包括在第三绝缘层的开口中的半透射导电层；像素电极和第一绝缘层之间的透明保护层；第四绝缘层，具有与形成在第三绝缘层中的开口对应的开口，第四绝缘层覆盖焊盘电极的端部；像素电极上的发光层；和发射层上的相对电极。

